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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of _____:

September 26, 2003

Huilong Zhu, et al. _____:

Group Art Unit:

Serial No. Divisional Application of
10/605,130 _____:

Examiner:

Filed: 9/10/2003 _____:

International Business Machines Corporation
2070 Route 52
Hopewell Junction, NY 12533

TITLE: STRUCTURE AND METHOD FOR SILICIDED METAL GATE TRANSISTORS

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to the duty of disclosure set forth in 37 C.F.R. 1.56, and further pursuant to the provisions of 37 C.F.R. 1.97 and 1.98, applicants hereby respectfully submit copies of the non-US patents and publications as listed on Form PTO-1449, attached hereto.

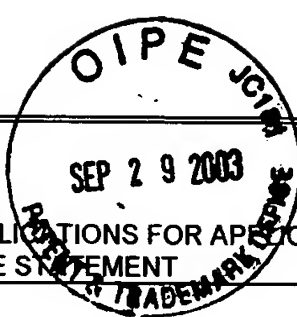
In citing these documents, no representation is made nor intended as to the pertinency or non-pertinency of the art, that better art than that listed is not available, or that other art is not applicable.

No fee is believed to be due for this submission. If any fees are required, however, the Commissioner is hereby authorized to charge such fees to Deposit Account No. 09-0458.

Respectfully submitted,
Huilong Zhu, et al.

By H. Daniel Schnurmann
H. Daniel Schnurmann, Agent
Registration No. 35,791
Telephone No. 845-894-2481

FIS920030283US1



FORM PTO-1449 (Modified)		ATTY. DOCKET NO. FIS920030283US1	SERIAL NO.
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT		APPLICANT: DORIS ET AL.	
(Use several sheets if necessary)		FILING DATE:	GROUP:

REFERENCE DESIGNATION U.S. PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	ISSUED DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPRO.)

FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
					YES NO

OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)

AH	S.B. Samavedam et al., "Silicon Materials – Processing, Characterization and Reliability Symposium," <u>Mater. Res. Soc. Proc.</u> , vol. 716, 2002, pp. 85-90.
AI	K. T. Nishinohara et al., "Regular Papers Short Notes & Review Papers" <u>Japan Jnl. App. Phys. Ltrs.</u> , pt 1, v. 40, 2001, pp. 2603-2606.
AJ	F. F. Zhao et al., "Silicon Materials – Processing, Characterization and Reliability Symposium," <u>Mater. Res. Soc. Proc.</u> , vol. 716, 2002, pp. 41-46.
AK	W. T. Liaw et al., "Letters" <u>Japan Jnl. App. Phys. Ltrs.</u> , pt 2, v. 36, n. 2A, 1997, pp. L89-92.

EXAMINER	DATE CONSIDERED
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.